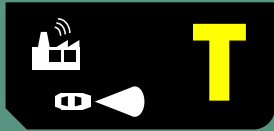




38th
International Electronics Manufacturing
Technology (IEMT)
Conference
2018



Modeling of Molded Electronic Package Warpage Characteristic with Cure Induced Shrinkage and Viscoelasticity Properties

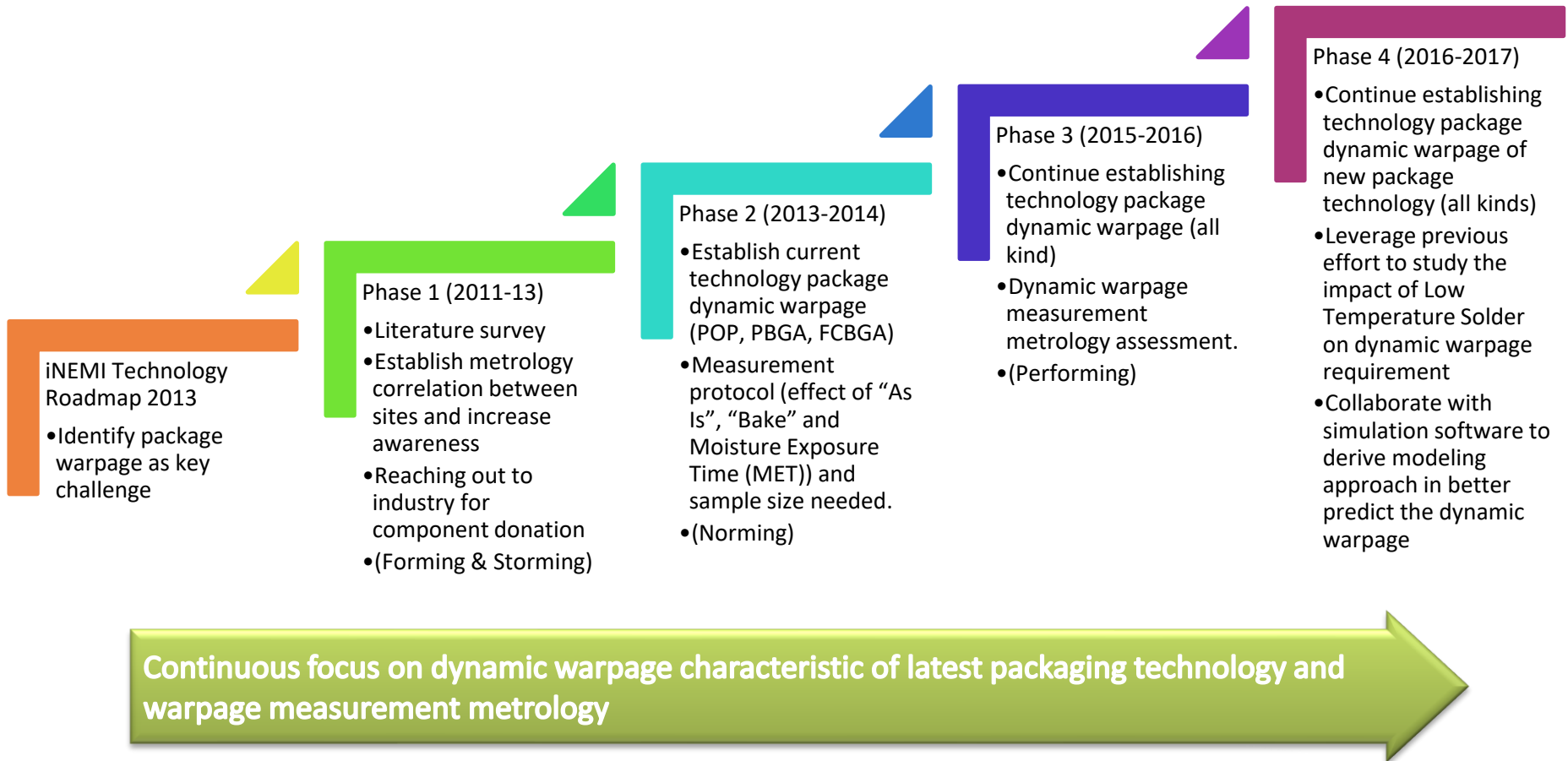
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iNEMI: Warpage Characteristics of Organic Packages, Phase 4



Project Scopes in Phase 4 SOW

Characterization of latest packaging technology

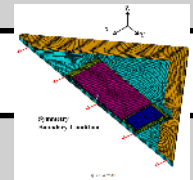
- Characterize emerging electronic packaging technology dynamic warpage behavior to develop a better understanding of the current development of package construction and material development as listed in Table I.
- Silicon Interposer and Embedded Silicon Bridge with different package stiffeners and constructions for Heterogeneous Packaging Solution
- Next generation of POP packages that leverages wafer level process for package construction which include Panel and Wafer level molding. These also include the use of new fiber reinforced mold material for warpage control.
- System In Package/Multi Chip Package (BGA) with different configuration and layout.
- Embedded Package (embedded silicon, actives and passives)

Assess the impact of Low Temperature Solder (LTS) on package dynamic warpage requirement

- To assess the impact of lower temperature solder on package warpage for those packages collected in Phase 2 and 3.
- To establish the risk level based on package technology with respect to warpage only.

Assessment the use FEA in optimizing package warpage

- Establish modeling optimization approach and tools requirement to enable higher accuracy prediction technique
- Compare modeling with experiment data and identify potential gaps for further development in FEA technique

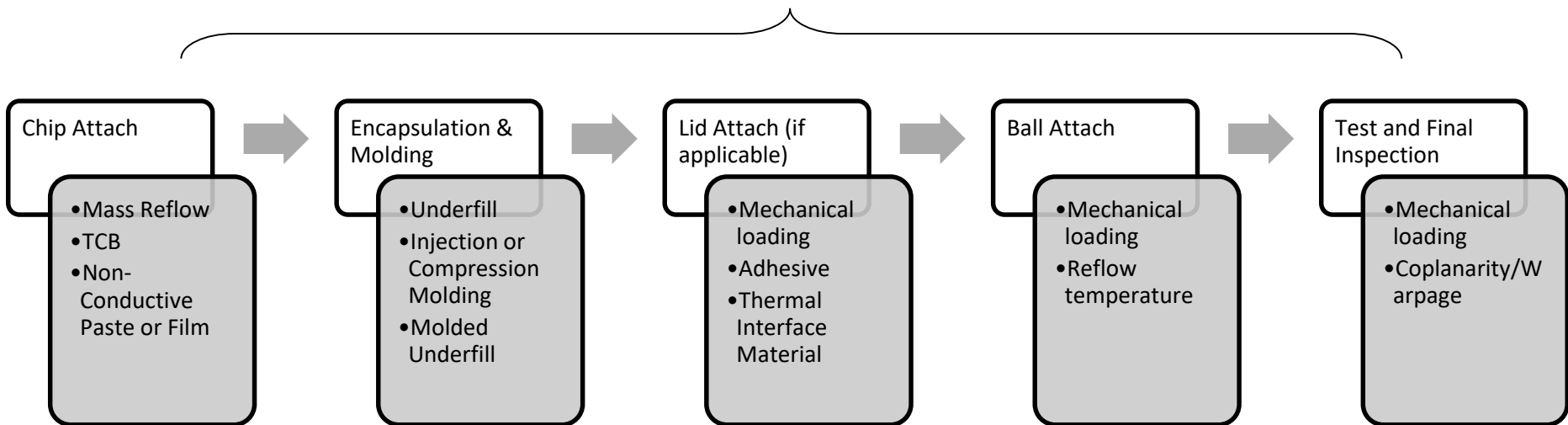
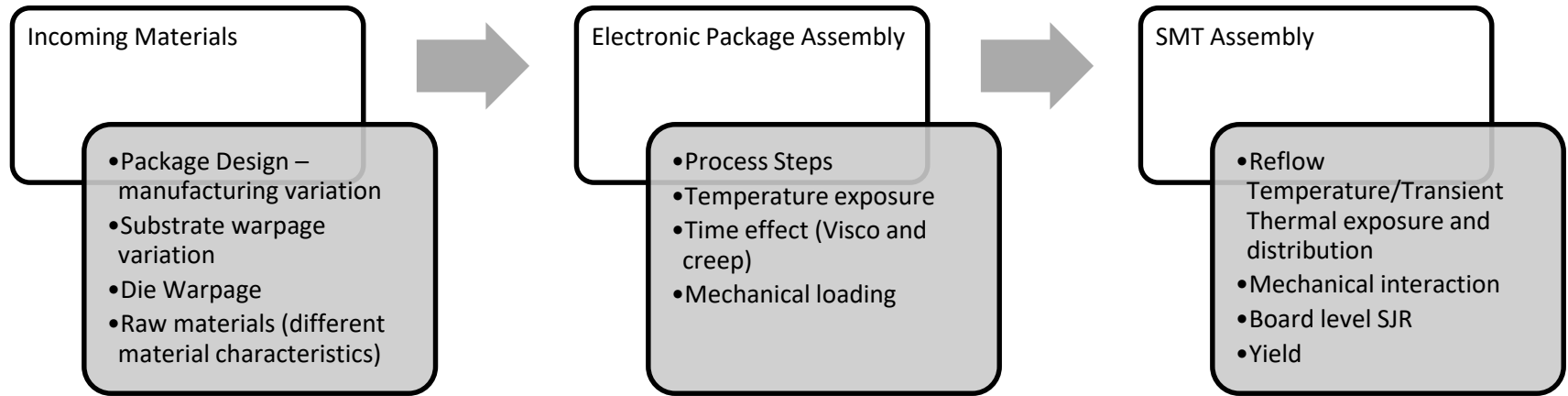


Content

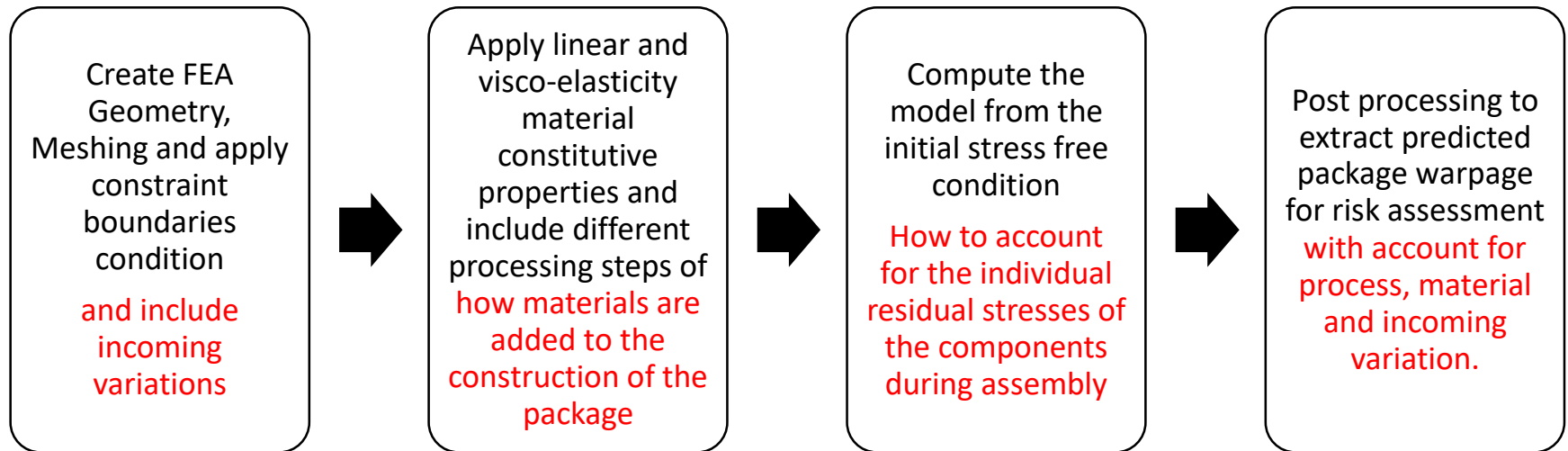
- Background and motivation
- Modeling approach and governing equations
- Sensitivity Studies
- Summary

Disclaimer: The work here covers some feasibility study which collaborated with iNEMI and we are not endorsing any software in particular.

Multi-physics in Assembly Process

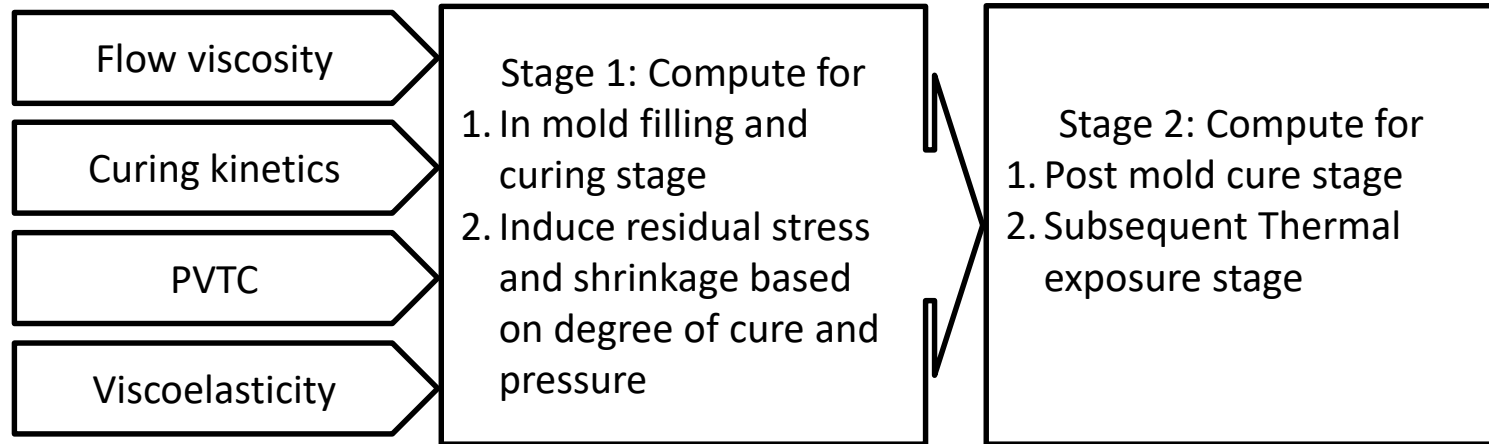


Current Modeling Approach is it Adequate?

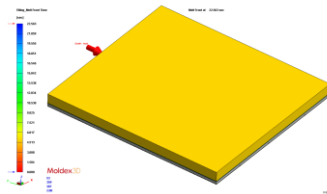


Significant effort needed to account for multi-physics interaction in packaging assembly for warpage prediction
 Many commercial available modeling tools are still working to refine the modeling needs.

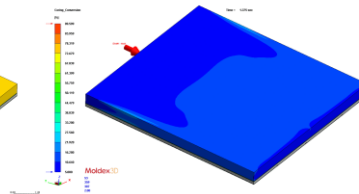
Moldex3D



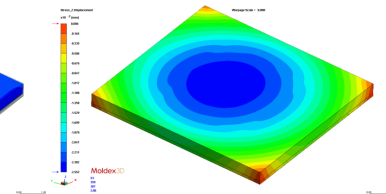
Filling



Curing



Post mold cure deformation



Moldex3D

Coupled mold flow, curing kinetics, visco-elasticity and shrinkage and conjugate heat transfer in one environment

Material Characterization in Moldex3D

Laboratory



MCR 502
Rotation
and
oscillation
tests for
viscoelastic
properties



TMA 4000
Coefficient of
thermal
expansion



DSC 8500
Transition
temperatures
and
crystallization
kinetics



DMA 2690
Dynamics
mechanism
analysis for
relaxation
modulus



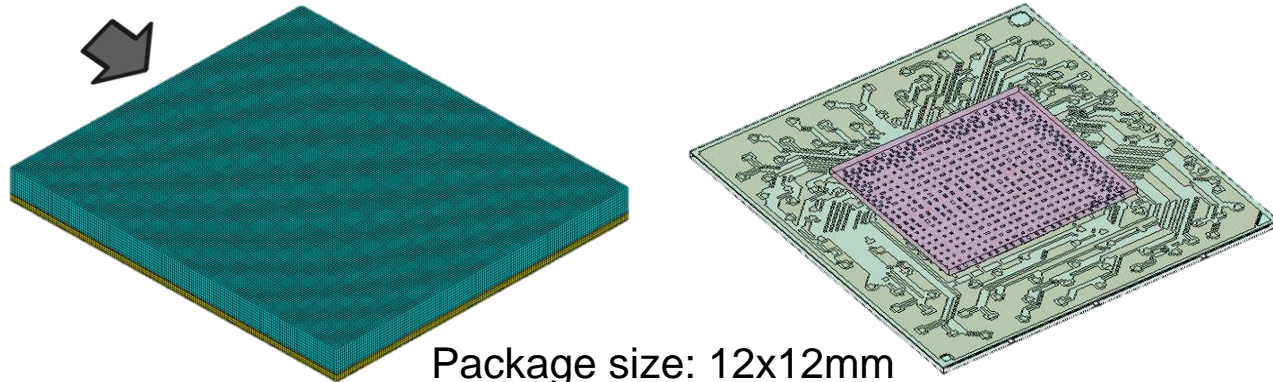
PT-6800
Specific
volume with
curing
(PVTC)



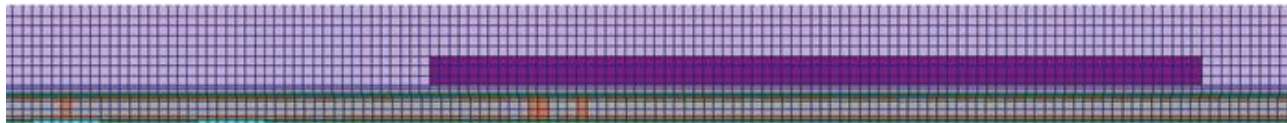
H5DR
Thermal
conductivity

Test Model for Demonstration

Mold flow direction

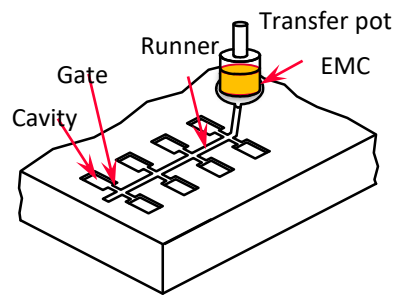


Package size: 12x12mm
 Package thickness: 0.61mm
 Mold thickness: 0.45mm



Materials	Modulus (MPa)	CTE (ppm)
Silicon	172800	3
Substrate	18190	14.4
Copper	110000	17
Dielectric	13170	6.3
Mold	Viscoelasticity	PVTC

Mold Flow Governing Equations



Mass balance

$$\frac{\partial \rho}{\partial t} + \nabla \cdot (\rho \mathbf{u}) = 0$$

Momentum balance

$$\rho \frac{D\mathbf{u}}{Dt} = \nabla \cdot \boldsymbol{\tau} - \nabla p + \rho \mathbf{g}$$

Energy balance

$$\rho C_p \left(\frac{\partial T}{\partial t} + \mathbf{u} \cdot \nabla T \right) = \nabla \cdot k \nabla T - \boldsymbol{\tau} : \dot{\boldsymbol{\gamma}} + S$$

Thermoset conversion balance

$$\frac{d\alpha}{dt} = (k_1 + k_2 \alpha^m)(1 - \alpha)^n$$

Density, ρ

Relationship between $\boldsymbol{\tau}$ and \mathbf{u} or viscosity, η

Heat capacity, C_p

Thermal conductivity, k

Conversion rate, α

Temperature-pressure-cure dependent volume, $V(T, P, C)$

Relaxation Modulus, G

CAE procedure



Flow/Cure behavior



Post mold cure analysis

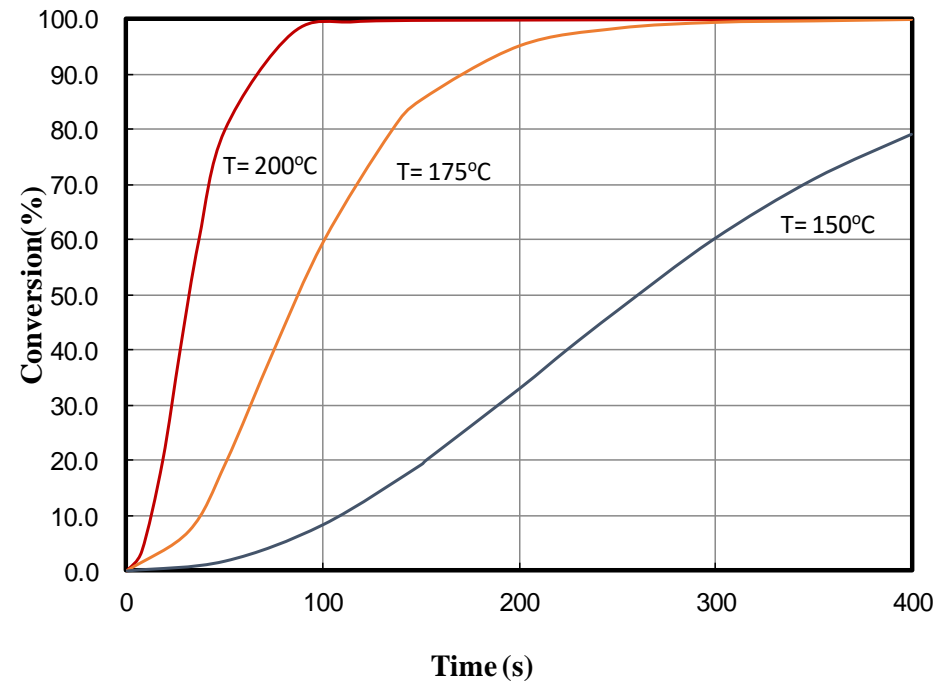
Curing Kinetics Mold Material Properties

The combined model to investigate the curing kinetics of the given mold because of its ability to accurately predict the experimental data. The combined model can be expressed as follows:

$$\frac{d\alpha}{dt} = (k_1 + k_2\alpha^m)(1 - \alpha)^n$$

$$k_1 = A_1 \exp\left(-\frac{E_1}{RT}\right)$$

$$k_2 = A_2 \exp\left(-\frac{E_2}{RT}\right)$$

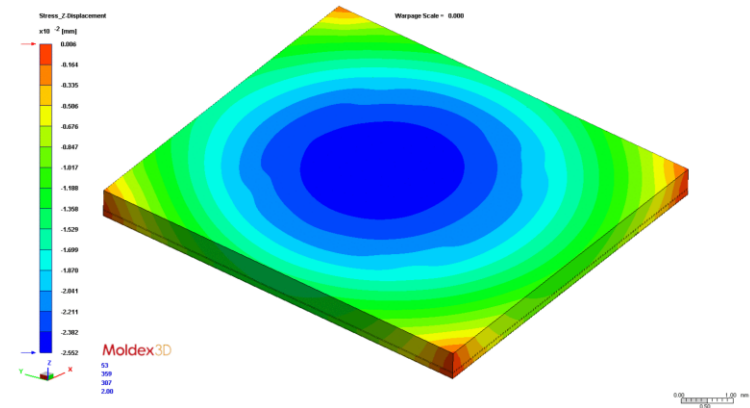


Structural Stress Governing Equations

Stress balance

$$\nabla \cdot \boldsymbol{\sigma}(t) = 0,$$

$$\boldsymbol{\sigma} = \mathbf{C}(\boldsymbol{\varepsilon} - \boldsymbol{\varepsilon}^{PVTC}), \boldsymbol{\varepsilon} = \frac{1}{2}(\nabla \mathbf{U} + \nabla \mathbf{U}^T)$$



Compute for thermal and cure induced strains can be expressed in the following PVTC equation for epoxy:

$$\boldsymbol{\varepsilon}^{PVTC} = VS(P, V, T, C)$$

PVTC Mold Material Properties

The two domain modified Tait model is used to formulate the specified volume of resin as below:

$$\frac{1}{V} = \frac{1}{V_{uncured}}(1 - \alpha) + \frac{1}{V_{cured}}\alpha$$

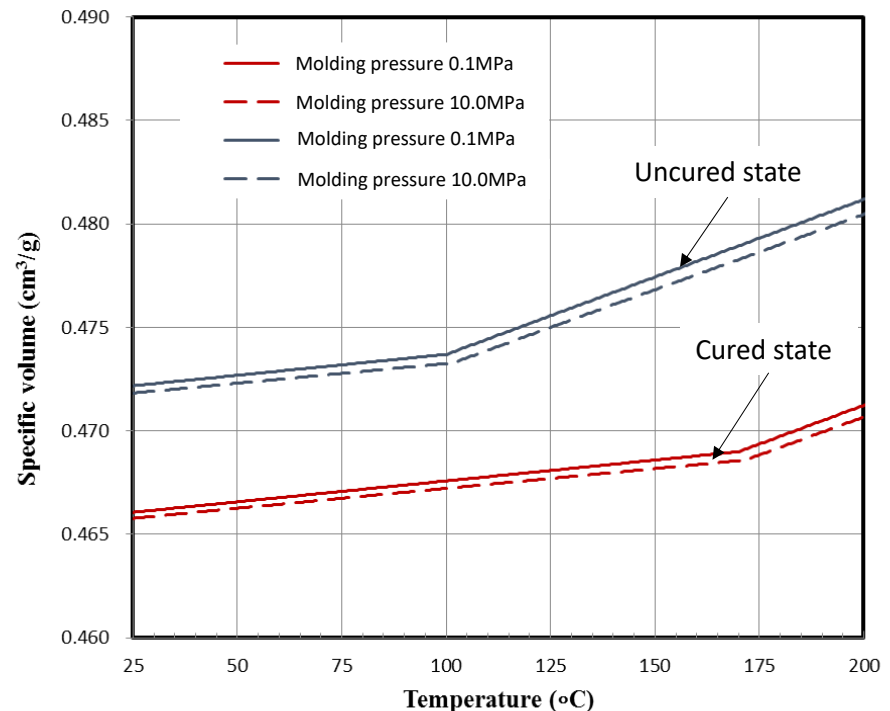
$$V_{cured/uncured} = V_0 \left[1 - C \ln \left(1 + \frac{P}{B} \right) \right]$$

$$V_0 = \begin{cases} b_{1S} + b_{2S}\bar{T}, & \text{if } T \leq T_t \\ b_{1L} + b_{2L}\bar{T}, & \text{if } T > T_t \end{cases}$$

$$B = \begin{cases} b_{3S} \exp(-b_{4S}\bar{T}), & \text{if } T \leq T_t \\ b_{3L} \exp(-b_{4L}\bar{T}), & \text{if } T > T_t \end{cases}$$

$$T_t = b_5 + b_6 P$$

$$\bar{T} = T - b_5, C = 0.0894$$

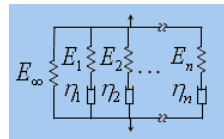


Viscoelasticity Governing Equations

- C is a tensor and function of relaxation

modulus $E(t, T,)$ curve:

$$C = C_{ijkl} = \frac{E(t)}{2(1+\nu)} (\delta_{ik}\delta_{jl} + \delta_{il}\delta_{jk}) + \frac{\nu E(t)}{(1+\nu)(1-2\nu)} \delta_{ij}\delta_{kl}$$



Viscoelasticity of Mold Materials

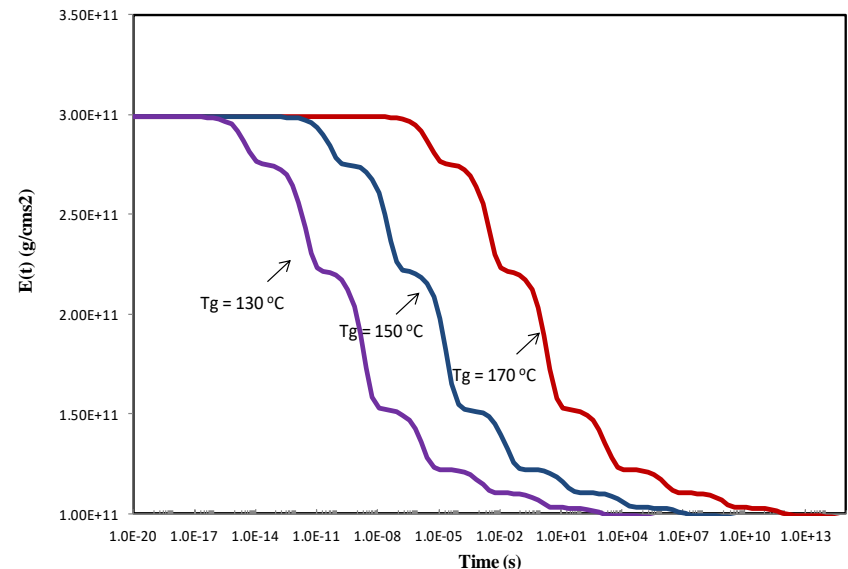
- Relaxation stiffness in VE analysis:

$$E(T, C, t) = E(T_{ref}, C_{ref}, t/a)$$

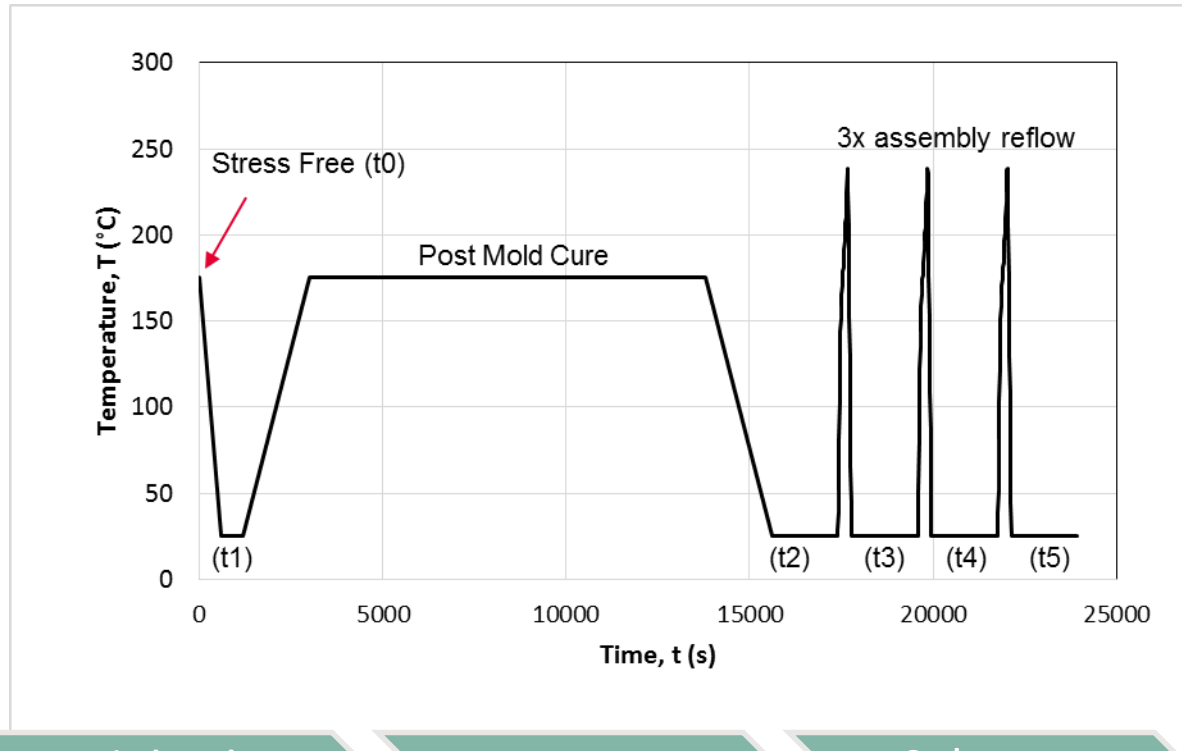
– where the temperature and curing shift factor

$$\log a_T = \frac{-C_1(T - T_{ref})}{C_2 + T - T_{ref}}$$

$$\log a_C = a_1 C^n + a_2 C^{(n-1)} + \dots + a_0$$

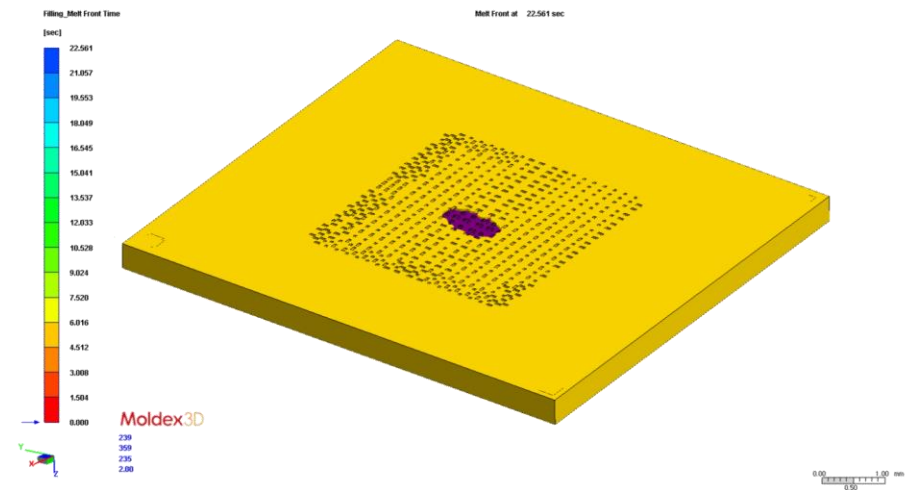
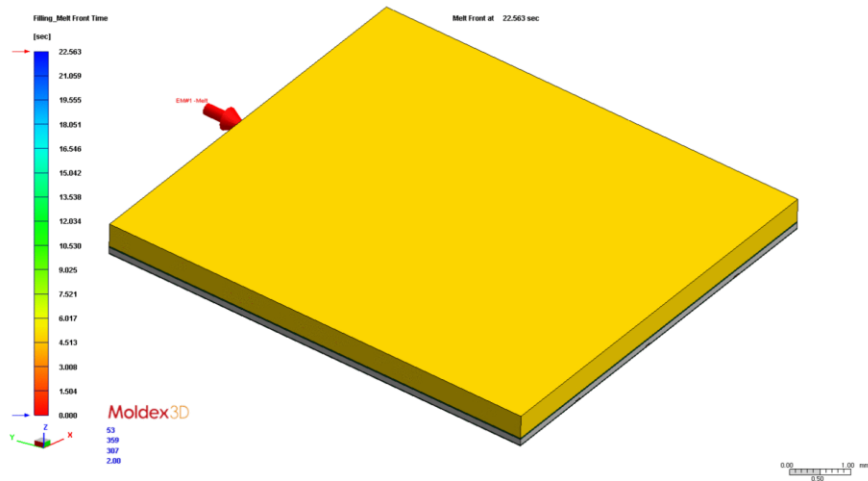


Loading Boundaries Condition

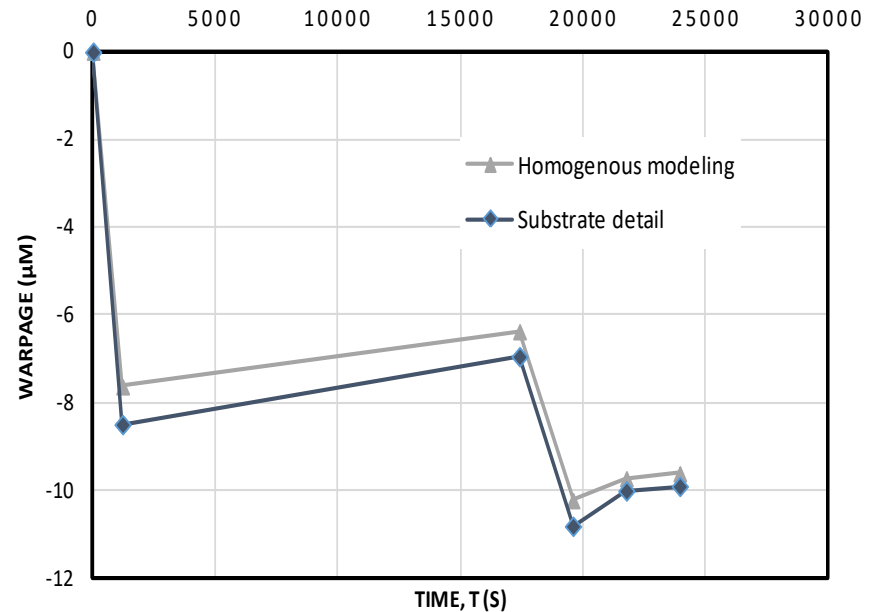
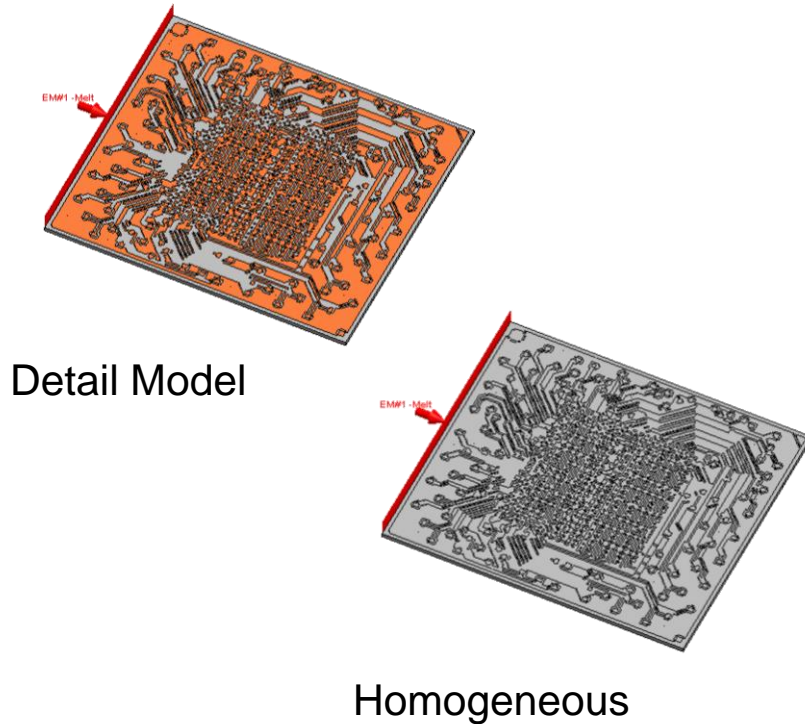


Mold Flow Simulation

The mold flow front encapsulates the cavity uniformly and has the potential to trap voids underneath the chip in C4 region.



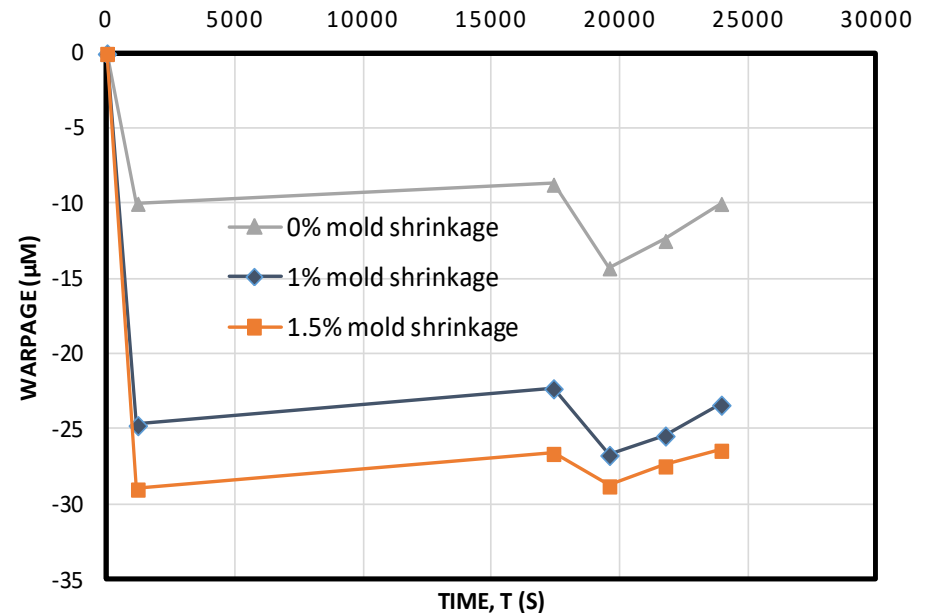
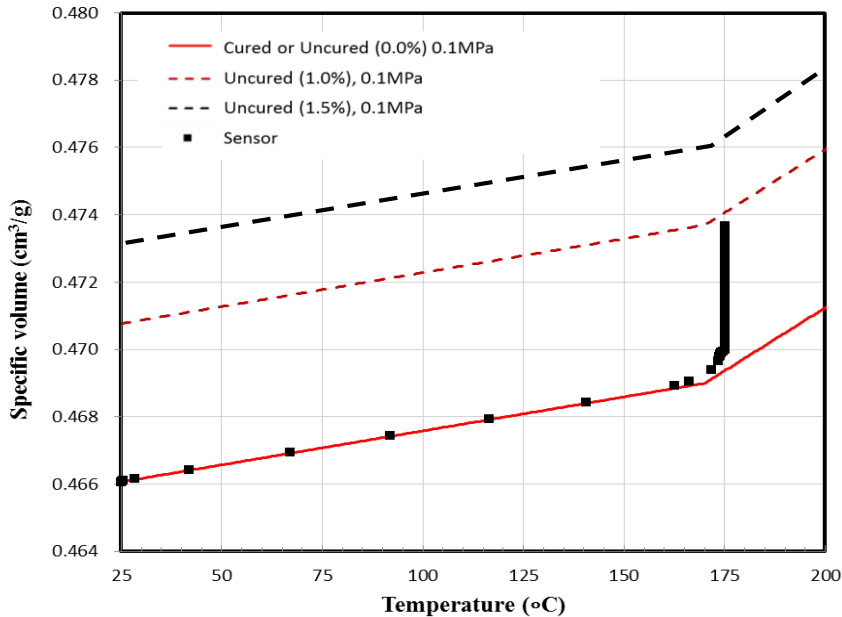
Effect of Detail vs Homogeneous Model



Detail Model – copper and dielectric patterns are taken into account
 Homogeneous – the effective mechanical properties are considered

The impact of the detail model for this case is ~3% (not significant) due to small and thin design

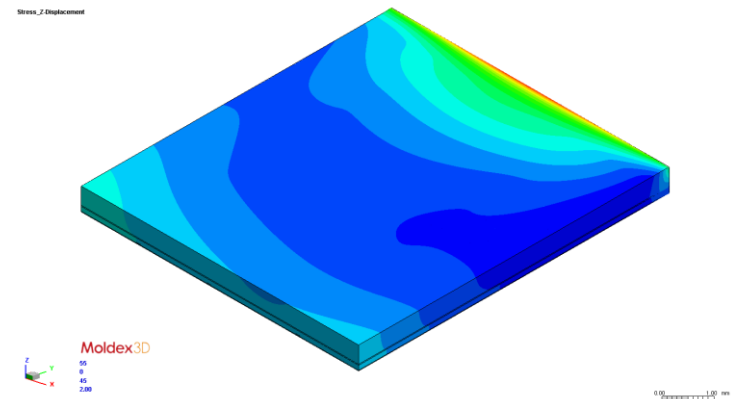
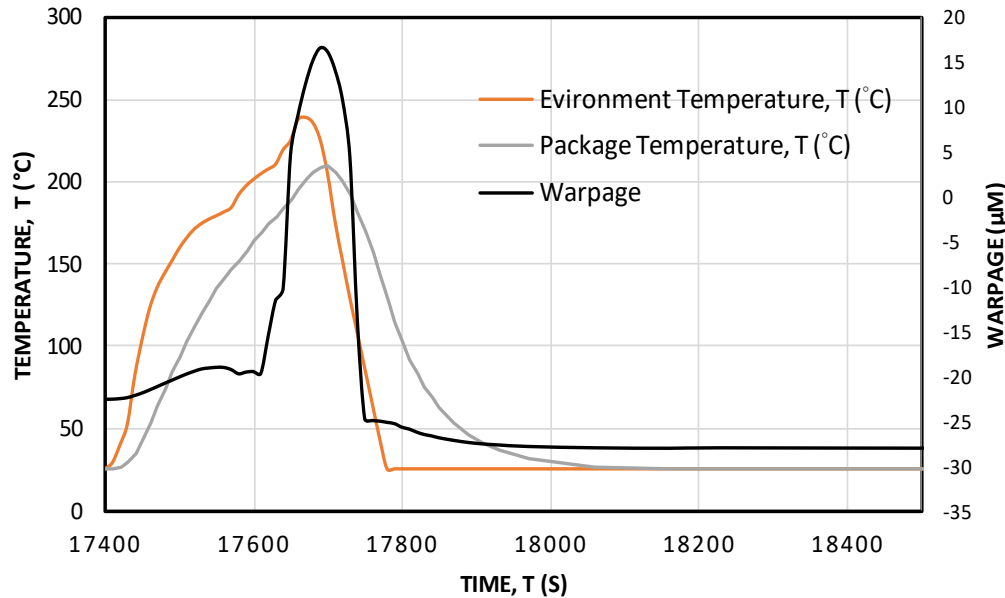
Effect of PVTC Properties



PVTC properties captures the volumetric change as a function of temperature for uncured and cured mold

The impact of mold shrinkage is significant. Typical FEA doesn't account for chemical shrinkage

Dynamic Warpage of Package

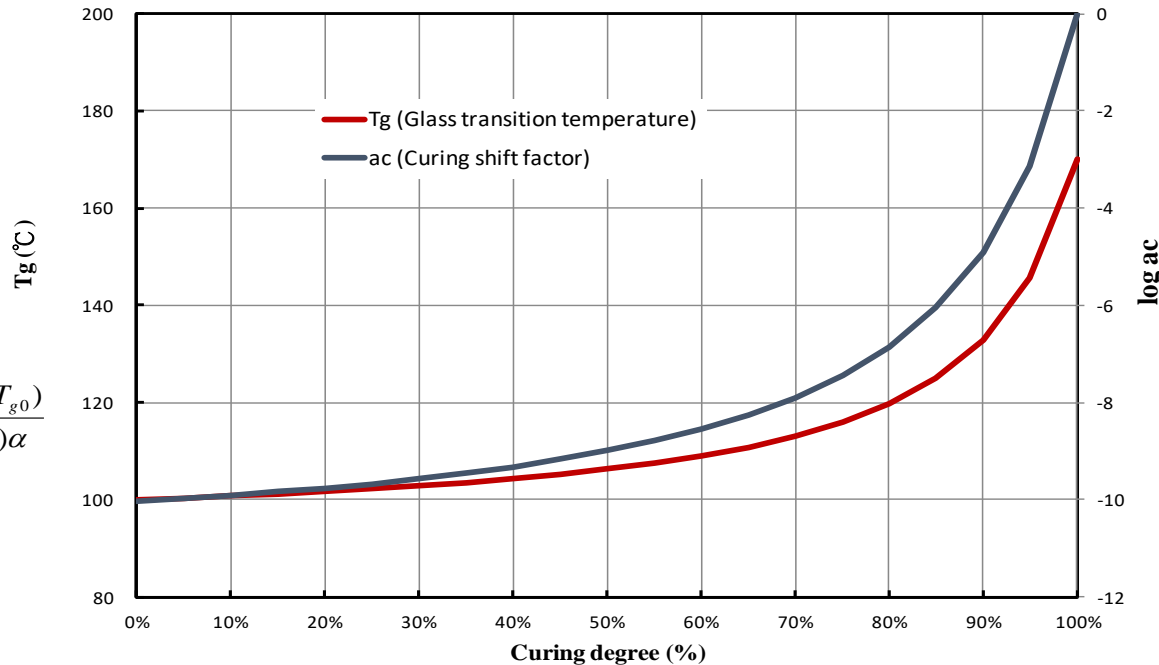


During the reflow cycle, the package warpage changes as a function of temperature. The package started off concave (-ve) at room temperature, then morph to convex at elevated temperature

Effect of Tg as a function of curing degree

DiBenedetto

$$T_g(\alpha) = T_{g0} + \frac{\lambda\alpha(T_{g1} - T_{g0})}{1 - (1 - \lambda)\alpha}$$

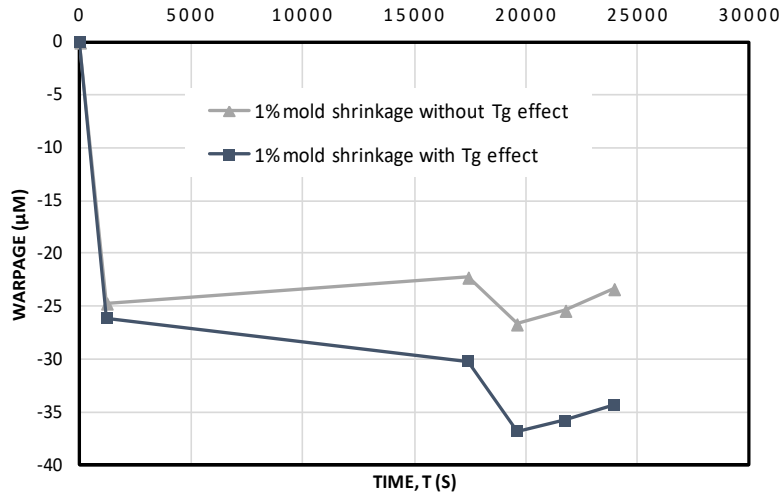


Vogel

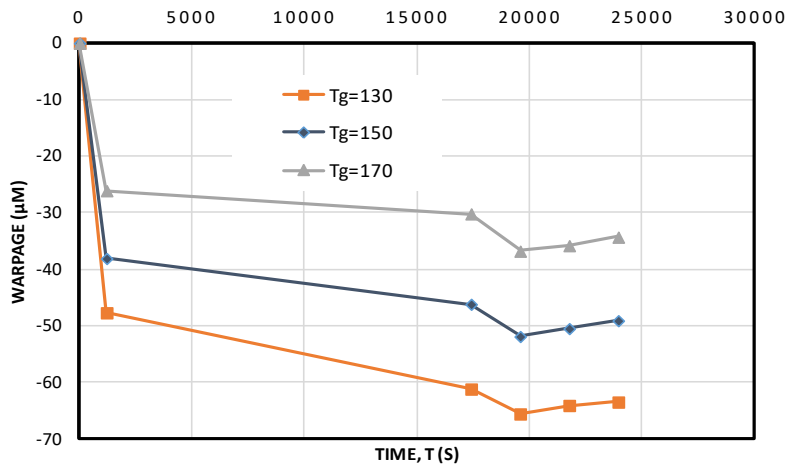
$$a_c = \exp\left(-\frac{\Delta H}{R}\left(\frac{1}{T_g(\alpha)} - \frac{1}{T_{g1}}\right)\right)$$

“DiBenedetto equation” is usually adopted for modeling the Tg as a function of conversion rate of reaction
the curing shift factor, ac, utilizes Vogel model

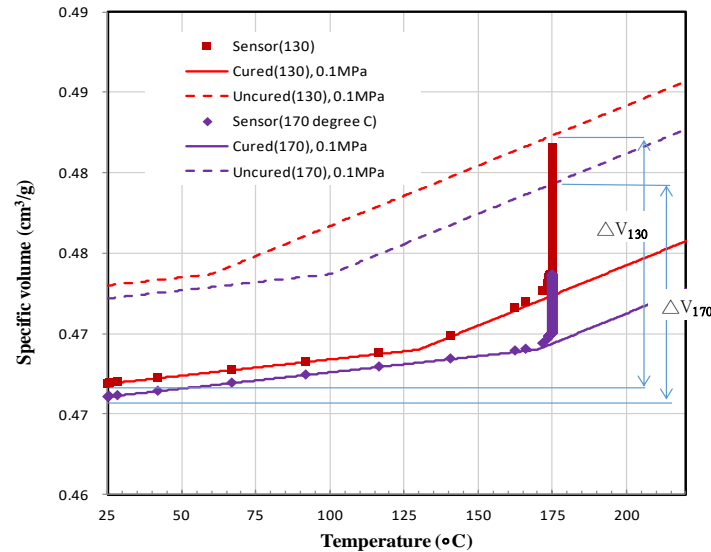
Effect of Tg



The evolution of Tg as a function of curing degree



Lower Tg gives rise to higher warpage magnitude



Summary

- Capturing the packaging assembly process involved requires significant effort in refining the assumptions, the numerical approach, and the analytical approach.
- The sensitivity model studied here only covered the molding process by capturing the mold flow and structural analysis based on fluid dynamics, PVTC, viscoelasticity with corresponding analytical equations and non-linear properties.
- The in-mold cure shrinkage which was represented by PVTC data, played a significant role in determining the final package warpage.
- A higher cure shrinkage can yield a higher package warpage.
- The impact of mold cure conversion rate on Tg and PVTC can change the characteristic of package warpage from uncured to fully cured mold.
- The modeling demonstrated that a higher cured Tg mold gives rise to a lower package warpage.
- The additional reflow cycles included in the model increases the package warpage as the result of changes in the viscoelasticity and stress relaxation.
- The next logical step is to evaluate other modeling approaches and validation that can mimic the actual assembly process as close as possible to enhance the prediction capability.

Package Technology Dynamic Warpage Measurement

Generous Donation of Samples from Industry

Package Type	Design	Phase 2 and 3 Package Consideration	Phase 4 Package Consideration (New focus areas)
PoP	Overmold TMV®		New PoP package (InFo-Integrated Fan out, WLP-wafer level packaging) Integrated memory and logic packages Latest MCEP (Molded Core Embedded Substrate) packages
	Expose Die TMV®		
	Bare Die PoP		
	Interposer PoP		
	Pre-stack PoP package		
	MCEP®	New variance - MCP	
	PoP Memories		
SiP	Overmold Multiple Chip Package (MCP)		Modem and High Bandwidth Memory Packages
FBGA	Overmold single die package		
FCBGA	with single or multi dies		Multi-chip packages
FCBGA with Lid	Organic and ceramic substrate		Silicon Interposer Packages and embedded bridge
PBGA	Ranges		

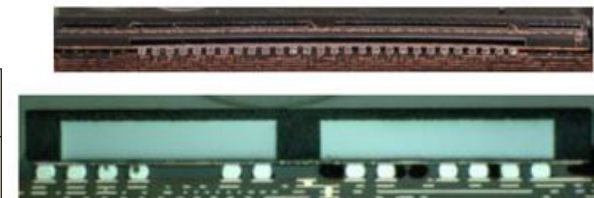
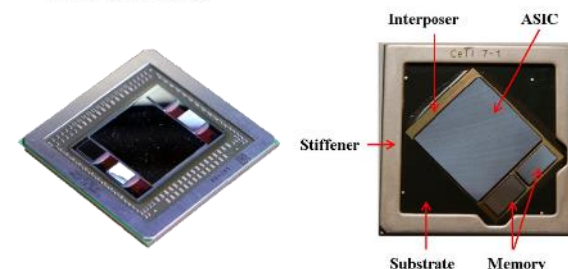
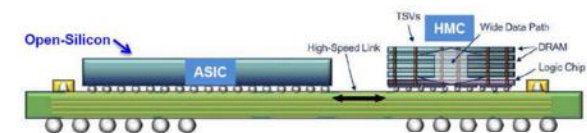
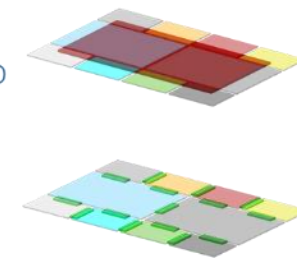


Photo source: Prismark/Binghamton University



Industry Standard 2.5D

EMIB



Focusing on new and advance package technologies

Pictures are mainly for illustration only